

	Application No.	Applicant(s)
Notice of Allowability	10/812,987	OZAWA ET AL.
	Examiner	Art Unit
	Thanh Y. Tran	2822
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.		
1. This communication is responsive to 2/22/06.		
2. The allowed claim(s) is/are <u>5-20</u> .		
 3. Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some* c) None of the: 1. Certified copies of the priority documents have been received. 		
2. Certified copies of the priority documents have been received in Application No		
3. Copies of the certified copies of the priority documents have been received in this national stage application from the		
International Bureau (PCT Rule 17.2(a)).		
* Certified copies not received:		
Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application. THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		
4. A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.		
5. CORRECTED DRAWINGS (as "replacement sheets") must be submitted.		
(a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached		
1) hereto or 2) to Paper No./Mail Date		
(b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date		
Identifying Indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).		
6. DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.		
Attachment(s) 1. ☑ Notice of References Cited (PTO-892)	5. ☐ Notice of Informal Pa	atent Application (PTO-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. ☐ Interview Summary (Paper No./Mail Date	
 Information Disclosure Statements (PTO-1449 or PTO/SB/08 Paper No./Mail Date <u>2/22/06</u> 		
Examiner's Comment Regarding Requirement for Deposit of Biological Material	8. 🛛 Examiner's Stateme	nt of Reasons for Allowance
T. Sivingion material	9. Other	·

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DETAILED ACTION

This application is in condition for allowance except for the presence of claims 1-4 to an invention non-elected without traverse. Accordingly, claims 1-4 have been cancelled.

Allowable Subject Matter

- 1. Claims 5-20 are allowed.
- 2. The following is an examiner's statement of reasons for allowance:

In claim 5, the patentability, at least in part, is a combination of: "a method of manufacturing a semiconductor device comprising: an isolation region is provided on a surface of the semiconductor substrate and includes an isolation trench; and a non-volatile memory cell comprising: a tunnel insulating film, a floating gate electrode provided on the tunnel insulating film; a control gate electrode above the floating gate electrode; and an interelectrode insulating film is provided between the control gate electrode and the floating gate electrode, the method comprising the steps of: forming the isolation trench by etching the semiconductor film, the insulating film and the semiconductor substrate; and annealing the floating gate electrode, the tunnel insulating film and the semiconductor substrate in water vapor atmosphere"; and in the combination with other claimed limitations.

3. The art of record does not disclose the above limitations, nor would it be obvious to modify the art of record so as to include the above limitations.

Shimizu et al (U.S. 6,555,427) or Shimizu et al (U.S. 6,818,508) discloses in figures 4A-4C a non-volatile semiconductor memory device comprising the step of: forming isolation trenches by etching the substrate 101 by use the masking materials 201, and the isolation insulating film 102. However, Shimizu et al does not teach the step of: annealing the floating

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gate electrode, the tunnel insulating film and the semiconductor substrate in water vapor atmosphere.

The references cited in the IDS filed on 2/22/06 do not teach or render obvious to modify 4. the art of record so as to include the above mentioned-limitations.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Thanh Y. Tran whose telephone number is (571) 272-2110. The examiner can normally be reached on M-F (9-6:30pm).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Zandra Smith can be reached on (571) 272-2429. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free)

Supervisory Patent Examiner

March 200

TYT